## **WEST Search History**

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DATE: Thursday, May 18, 2006

Set Name	<u>Query</u>	Hit Count
DB = PGPB, USPT, USOC, EPAB, JPAB, DWPI, TDBD; PLUR = YES; OP = ADJ		
L13	L12 and substrate	212
L12	L11 and silicon layer	213
L11.	L9 and polishing	388
L10	L9 and HF dip	23
L9	L8 and oxide layer	1140
L8	L7 and wafer	2548
L7	L6 and (die or dice)	5554
L6	(SOI or silicon on insulator)	68203
L5	L4 and polishing	. 8
L4	L3 and (SOI or silicon on insulator)	12
L3	HF dip process	30
L2	(SOI or silicon on insulator) same interconnect line	81
L1	(SOI or silicon on insulator) and interconnect line	607
	DB=PGA L13 L12 L11 L10 L9 L8 L7 L6 L5 L4 L3 L2	L13 L12 and substrate L12 L11 and silicon layer L11 L9 and polishing L10 L9 and HF dip L9 L8 and oxide layer L8 L7 and wafer L7 L6 and (die or dice) L6 (SOI or silicon on insulator) L5 L4 and polishing L4 L3 and (SOI or silicon on insulator) L3 HF dip process L2 (SOI or silicon on insulator) same interconnect line

END OF SEARCH HISTORY

For 10/784566